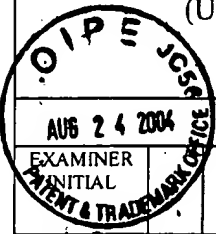


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U.S. PATENT DOCUMENTS								
	EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	<i>cl</i>	A	6,523,961	2/25/2003	Ilkov et al.	353	99	12/7/2000
		B	6498,870	12/24/2002	Wu et al.	385	18	4/20/1998
		C	6,114,044	9/5/2000	Houston et al.	428	447	5/30/1997
		D	5,512,374	4/30/1996	Wallace et al.	428	422	5/9/1994
		E	5,411,769	5/2/1995	Hornbeck	427	534	9/29/1993
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
<i>cl</i>	F	R. Legtenberg et al., "Stiction of surface micromachined structures after rinsing and drying: model and investigation of adhesion mechanisms", <u>Sensors and Actuators A</u> , 43, pp 230-238, 1994						
	G	H. Guckel et al., "Fabrication of Micromechanical Devices from Polysilicon Films with Smooth Surfaces", <u>Sensors and Actuators</u> , 20, pp 117-122 (1989)						
	H	R. Alley et al., "The Effect of Release-Etch Processing on Surface Microstructure Stiction", Proc. IEEE Solid-State Sensor & Actuator Workshop, Hilton Head Island, S.C., pp. 202-207 (1992)						
	I	D. Kobayashi et al., "An Integrated Lateral Tunneling Unit" Proc. IEEE Micro Electro Mechanical Systems, Travemunde Germany, pp 214-219, (1992)						
	J	N. Takeshima et al. Proc. Int. Conf. Solid-State Sensors & Actuators (Transducers '91), San Francisco, CA, pp. 63-66, (1991, IEEE, New York)						
	K	C. Mastrangelo and C. Hsu, "Mechanical Stability and Adhesion of Microstructures Under Capillary Forces - Part I: Basic Theory" <u>Journal of Microelectromechanical Systems</u> , Vol. 2, No. 1 (March 1993) pp. 33-43						
	L	C. Mastrangelo and C. Hsu, "Mechanical Stability and Adhesion of Microstructures Under Capillary Forces - Part II: Experiments" <u>Journal of Microelectromechanical Systems</u> , Vol. 2, No. 1 (March 1993) pp. 44-55						
EXAMINER <i>Clasad</i>				DATE CONSIDERED <i>9/24/04</i>				
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